

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants :Sakae KOYATA et al. Group Art Unit : 1792  
Appl. No. : 10/562,236 Examiner : Kin Chan Chen  
Filed : February 7, 2007 Confirmation No. : 3799  
For : MANUFACTURING METHOD OF SILICON WAFER

## AMENDMENT UNDER 37 C.F.R. § 1.111

Commissioner for Patents  
U.S. Patent and Trademark Office  
Customer Service Window, Mail Stop **AMENDMENT**  
Randolph Building  
401 Dulany Street  
Alexandria, VA 22314

Sir:

This Amendment is responsive to the Office Action mailed January 29, 2009. Applicants respectfully request reconsideration and withdrawal of each of the rejections of the outstanding Office Action, and request allowance of all the claims pending herein. Inasmuch as the three-month shortened statutory period is set in the Office Action to expire on April 29, 2009, this response is being filed in a timely manner and no additional fee or extension of time is deemed necessary. Should any extension of time or fees be required to maintain pendency of the application, however, the same is hereby requested and authorization is hereby provided to charge any fees to Deposit Account No. 19-0089.

**Amendments to the Abstract** begin on page 2 of this paper.

**Amendments to the Claims** begin on page 4 of this paper.

**Remarks** begin on page 6 of this paper.